

10/031842

531 Rec'd PCT/P. 22 JAN 2002

[10191/2169]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s) : Volker BECKER et al. *7A
9/12/02*
 Serial No. : To Be Assigned
 Filed : Herewith
 For : DEVICE AND METHOD FOR ETCHING A SUBSTRATE
 BY USING AN INDUCTIVELY COUPLED PLASMA
 Examiner : To Be Assigned
 Art Unit : To Be Assigned

Assistant Commissioner for Patents
 Washington, D.C. 20231

PRELIMINARY AMENDMENT AND
37 C.F.R. § 1.125 SUBSTITUTE SPECIFICATION STATEMENT

SIR:

Kindly amend the above-captioned application before examination, as set forth below.

IN THE SPECIFICATION AND ABSTRACT:

In accordance with 37 C.F.R. § 1.121(b)(3), a Substitute Specification (including the Abstract, but without claims) accompanies this response. It is respectfully requested that the Substitute Specification (including Abstract) be entered to replace the Specification of record.

IN THE CLAIMS:

On the first page of the claims, first line, change "What is claimed is:" to --WHAT IS CLAIMED IS:--.

Please cancel, without prejudice, claims 1 to 32 in the underlying PCT application.

Please add the following new claims:

--33. (New) A device for etching a substrate, comprising: